

<b>Notice of Allowability</b>	Application No.	Applicant(s)
	10/519,623	MURRELL, ADRIAN
	Examiner	Art Unit

  

Meenakshi S. Sahu	2881	
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-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address--

All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTO-85) or other appropriate communication will be mailed in due course. **THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS.** This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.

1.  This communication is responsive to 9/26/2007.
2.  The allowed claim(s) is/are 1-13.
3.  Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
  - a)  All
  - b)  Some\*
  - c)  None
  1.  Certified copies of the priority documents have been received.
  2.  Certified copies of the priority documents have been received in Application No. \_\_\_\_\_.
  3.  Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)).

\* Certified copies not received: \_\_\_\_\_.

Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application.  
**THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.**

4.  A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.
5.  CORRECTED DRAWINGS ( as "replacement sheets") must be submitted.
  - (a)  including changes required by the Notice of Draftsperson's Patent Drawing Review ( PTO-948) attached
    - 1)  hereto or 2)  to Paper No./Mail Date \_\_\_\_\_.
  - (b)  including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date \_\_\_\_\_.

Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).
6.  DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.

**Attachment(s)**

1.  Notice of References Cited (PTO-892)
2.  Notice of Draftsperson's Patent Drawing Review (PTO-948)
3.  Information Disclosure Statements (PTO/SB/08),  
Paper No./Mail Date 9/26/2007
4.  Examiner's Comment Regarding Requirement for Deposit of Biological Material
5.  Notice of Informal Patent Application
6.  Interview Summary (PTO-413),  
Paper No./Mail Date \_\_\_\_\_.
7.  Examiner's Amendment/Comment
8.  Examiner's Statement of Reasons for Allowance
9.  Other \_\_\_\_\_.

  
 Jack I. Berman  
 Primary Examiner

## DETAILED ACTION

### ***Allowable Subject Matter***

1. Receipt is acknowledged of Applicant's reply and remarks filed September 26, 2007, in response to the Examiner's comments set forth in the Office Action of June 26, 2007.
2. Claims 1, 10, 12 and 13 have been amended. Claims 1, 10 and 13 are now allowed.

## REASONS FOR ALLOWANCE

3. The following is an examiner's statement of reasons for allowance:

**Regarding claim 1**, prior art fails to disclose a wafer support apparatus for an ion implanter having an implantation chamber for receiving an ion beam, comprising a wafer holder for holding a wafer in the implantation chamber during implantation, an arm carrying the wafer holder in the implantation chamber and having an arm portion adjacent the wafer holder which is at least intermittently exposed to the ion beam during implantation, and an arm shield mechanism on the arm and having a plurality of shielding surfaces which can be selectively disposed to shield said arm portion from said at least intermittent exposure to the ion beam.

**Regarding claim 10**, prior art fails to disclose a method for protecting an arm of a wafer support apparatus for an ion implanter, the implanter having an implantation chamber for receiving an ion beam, the arm carrying a wafer holder in the implantation chamber

and having an arm portion adjacent the wafer holder which is at least intermittently exposed to the ion beam during wafer implantation, the method comprising: disposing a first shielding surface of a shield mechanism on the arm to shield said exposed arm portion from said at least intermittent exposure to the ion beam for a pre-determined number of processes, and disposing a second shielding surface to protect the said exposed arm portion after a pre-determined number of wafer processes or if the ion species in the ion beam is changed.

Regarding claim 13, prior art fails to disclose a shield apparatus for mounting on an arm carrying a wafer holder in an implantation chamber of an ion implanter, said shield apparatus being arranged for protecting the arm from ions in an ion beam during a wafer ion implantation process, said apparatus comprising a plurality of shield portions, each being movable between a first and second position with respect to the arm, so that during an ion implantation process, ions in the ion beam are prevented from hitting the arm by a shield portion in the first position, and substantially no ions in the ion beam hit a shield portion in the second position.

4. Claims 2 – 9, 11 and 12 are allowed by virtue of their dependency on claims 1 and 10.

### ***Conclusion***

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably

accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Meenakshi S. Sahu whose telephone number is 571-270-3101. The examiner can normally be reached on Monday - Friday 8AM - 5PM est.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Robert H. Kim can be reached on 571-272-2293. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

*MS*

Meenakshi S. Sahu  
November 6, 2007

*Jack I. Berman*  
Jack I. Berman  
Primary Examiner